

Docket No.: 55071-268



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of : Customer Number: 20277  
Xuelong SHI, et al. : Confirmation Number: 9791  
Serial No.: 10/626,864 : Group Art Unit:  
Filed: July 25, 2003 : Examiner:  
For: AUTOMATIC OPTICAL PROXIMITY CORRECTION (OPC) RULE GENERATION

INFORMATION DISCLOSURE STATEMENT

Mail Stop IDS  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each non-English language reference was first cited in a corresponding foreign application search report or office action and its relevance discussed therein. A copy of the

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foreign search report or office action, together with an English language version thereof, is attached for the Examiner's information.

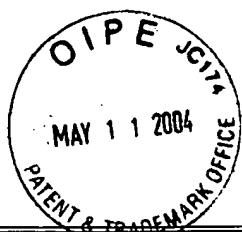
Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

Michael E. Fogarty  
Registration No. 36,139

600 13<sup>th</sup> Street, N.W.  
Washington, DC 20005-3096  
(202) 756-8000 MEF:gav  
Facsimile: (202) 756-8087  
**Date: May 11, 2004**



SHEET 1 OF 1

<b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  <b>(PTO-1449)</b>			ATTY. DOCKET NO. <b>55071-268</b>	SERIAL NO. <b>10/626,864</b>			
			APPLICANT <b>Xuelong SHI, et al.</b>				
			FILING DATE <b>July 25, 2003</b>	GROUP			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code <sub>2</sub> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
	US	<b>5,621,652</b>	<b>04/15/1997</b>	<b>Eakin</b>			
	US	<b>5,682,323</b>	<b>10/28/1997</b>	<b>Pasch et al.</b>			
	US	<b>5,821,014</b>	<b>10/13/1998</b>	<b>Chen et al.</b>			
	US	<b>6,077,310</b>	<b>06/20/2000</b>	<b>Yamamoto et al.</b>			
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	US	<b>6,421,820 B1</b>	<b>07/16/2002</b>	<b>Mansfield et al.</b>			
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	US						
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<b>FOREIGN PATENT DOCUMENTS</b>							
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Code <sub>3</sub> -Number <sub>4</sub> -Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
		<b>WO 99/14636</b>	<b>03/25/1999</b>	<b>NUMERICAL TECHNOLOGIES, INC.</b>		<input checked="" type="checkbox"/>	
<b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
		<b>HEWAK, Daniel., et al.</b> "Fabrication of tapers and lenslike waveguides by a microcontrolled dip coating procedure." <i>Applied Optics</i> , Volume 27, Number 21, November 1, 1988, pp. 4562-4564					
		<b>TORRES, J.A., et al.</b> "Contrast-based assist feature optimization photolithography." <i>Optical Microlithography XV</i> , Santa Clara CA, March 5-8 2002, Volume 4691, pp. 179-187, XP 000118756, ISSN: 0277-786X					
EXAMINER				DATE CONSIDERED			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.